

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

**Confirmation No.: 2987**

Takushi YOSHIDA, et. al.

Date: August 23, 2007

Serial No.: 10/541,507

Group Art Unit: 1763

Filed: July 8, 2005

Examiner: Sylvia MacARTHUR

For: SUBSTRATE PROCESSING SYSTEM, SUBSTRATE PROCESSING  
APPARATUS, PROGRAM AND RECORDING MEDIUMVIA EFS-WEB

Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

**RESPONSE TO RESTRICTION REQUIREMENT**  
**REMARKS/ARGUMENT**

This Response is filed in reply to the Restriction Requirement dated July 30, 2007.

Applicant elects the invention of Group I, identified as claims 40-76, drawn to a substrate processing system.

Applicant reserves the right to file a divisional application directed to the subject matter covered in the non-elected claims.

Early and favorable consideration of the present application is earnestly solicited.

If this communication is filed after the statutory time period had elapsed and no separate Petition is enclosed, the Commissioner for Patents is petitioned, under 37 C.F.R. §1.136(a), to extend the time for filing a response to the outstanding Office Action by the number of months which will avoid abandonment under 37 C.F.R. §1.135. The fee under 37 C.F.R. § 1.17 should be charged to our Deposit Account No. 15-0700.

Respectfully submitted,

THIS CORRESPONDENCE IS BEING  
SUBMITTED ELECTRONICALLY  
THROUGH THE UNITED STATES  
PATENT AND TRADEMARK OFFICE  
EFS FILING SYSTEM  
ON AUGUST 23, 2007



MAX MOSKOWITZ

Registration No.: 30,576

OSTROLENK, FABER, GERB & SOFFEN, LLP  
1180 Avenue of the Americas

New York, New York 10036-8403

Telephone: (212) 382-0700